

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1 of 1

Application Number	10/797,046
Filing Date	March 11, 2004
First Named Inventor	Jung-hyun Lee et al.
Examiner Name	SARA W CRANE
Attorney Docket No.	030681-000634

U.S. PATENT DOCUMENTS

Examiner Initials	Document Number - Kind Code	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Figures Appear
	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume/issue number(s), publisher, city and/or country where published
/O.N./	Sneh, Oler et al., Thin film atomic layer deposition equipment for semiconductor processing, Thin Solid Films 402 (2002) 248-261
/O.N./	Copy of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929
/O.N./	English Translation of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929

Examiner Signature	/Ori Nadav/ (02/01/2008)	Date Considered	
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